

EUV Lithography Explained—

EUVL short course during 2019 EUVL Workshop

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If you're ready to learn more about EUV Lithography – the technology that is enabling the extension of Moore's Law – then this short course is for you. Taught by contributors and the editor of the bestseller EUVL Lithography (second edition) from SPIE Press, this course will explain the fundamentals, challenges and status of EUVL. Conveniently scheduled in the Berkeley area on Monday June 10, 2019, during the 2019 EUVL Workshop, this course can get you up to speed on EUVL.

EUV Lithography technology consists of many sub-areas which are specific to 13.5 nm, including source, mask, optics, resist and patterning. The course has been designed to provide people new to EUVL with a valuable overview of all its areas, while those specializing in one area of EUVL can learn about other areas. Students will benefit from an entire day of exploring the highlights of different aspects of EUVL.

The course will be taught by Dr. Vivek Bakshi, editor EUV Lithography; Professor Jinho Ahn of Hanyang University; and Patrick Naulleau, Director of the Center for X-Ray Optics at Lawrence Berkeley National Laboratory. Instruction starts with an overview of EUVL – what it is, why we need it and how it differs from 193 immersion lithography. In addition:

- Bakshi will cover the fundamentals of EUV sources and survey current source technology to increase your understanding of the current challenges and how we can continue getting more and more power from EUV sources.
- Ahn will cover what an EUV mask does, how to pattern and manufacture it, and how to inspect, repair, clean, and maintain it.
- Naulleau will describe EUVL patterning, including the topics of etendue, EUV resists, stochastics, and out of band radiation.

The course will conclude with a wrap-up of EUVL's current status, challenges and future. We encourage questions and discussion in this course and look forward to sharing our knowledge of EUVL. Students will receive a bound copy of EUV Lithography (2nd Edition, SPIE Press) and a printed copy of the lecture notes.



You can find more information about this short course at <http://euvlitho.com/euv-lithography-short-course/>. To register, please visit <http://euvlitho.com/euv-lithography-short-course/>.

